



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

PATENT

In re application of: Ni *et al.*

Application No.: 09/347,583

Filed: June 30, 1999

Title: MOVEABLE BARRIER FOR MULTIPLE ETCH
PROCESSES

Attorney Docket No.:
LAM1P111/P0513

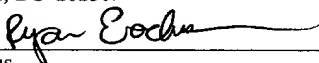
Examiner: C. Brown

Group: 1765

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I hereby certify that this paper and the documents and/or fees referred to as attached therein are being deposited with the United States Postal Service on October 18, 2002 in an envelope as "Express Mail Post Office to Addressee" service under 37 CFR §1.10, Mailing Label Number **EL937781052US**, addressed to the Commissioner for Patents, Washington, DC 20231.


Ryan Eachus

RESPONSE D

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

This reply and the enclosed remarks are submitted in response to the non-final Office Action mailed on June 18, 2002. Applicants submit that the attached amendments and remarks fully address the issues raised in the Office Action.

AMENDMENTS

In the Claims:

Please AMEND the claims as follows:

5/21/02
B. 8. (Once Amended) A plasma processing apparatus comprising:

a chuck for supporting a wafer; and

a moveable barrier having a first position and a second position, wherein the first position is capable of restricting diffusion of gases over the wafer within the